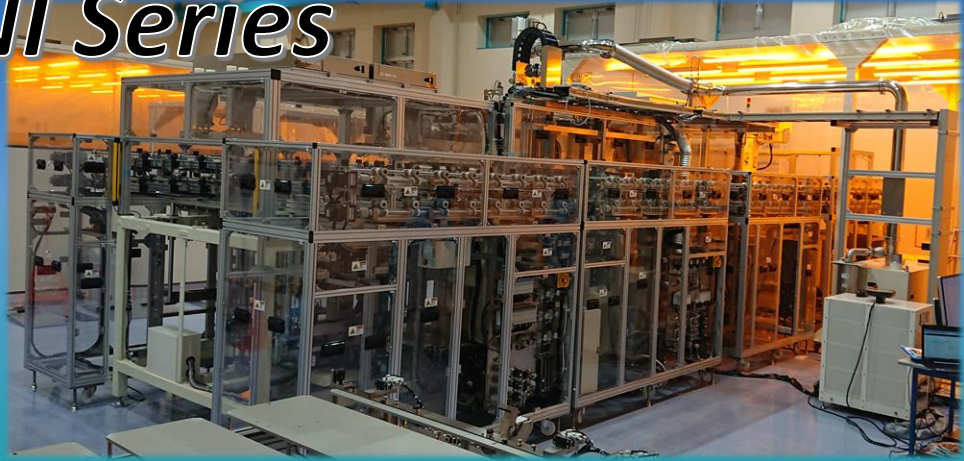


Nano Imprinting Equipment for large size panel

SENI Series



Our series enable continuous nano imprinting on large panel !

Equipment overview

This Equipment performs large-area nanoimprinting under vacuum using a flexible replica mold.

Feature

Applicable to large size panel

Panel size : Up to 1,100mm x 1,300mm
Trays are used for small panels.

Vacuum process

By processing under vacuum, it is possible to mold even closed patterns such as pillars.
Vacuum : 10Pa or less

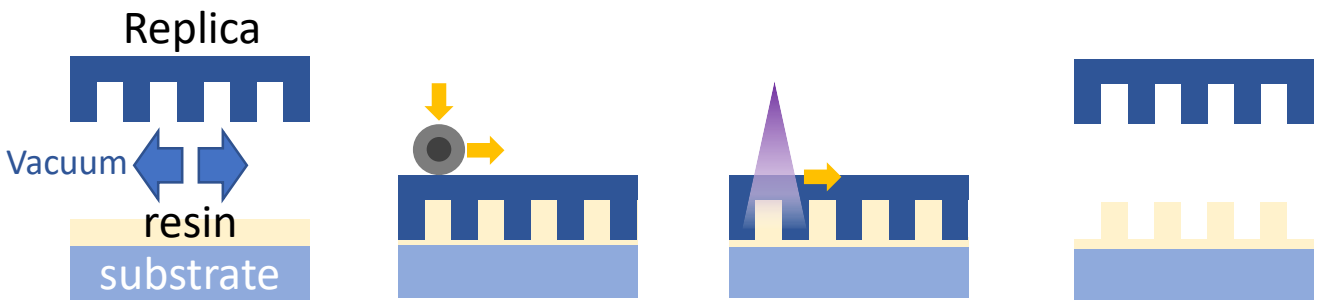
Additional pressure by roller

The values of roller pressure can be set.

Customizing

We can propose a mass production equipment according to demonstration of a prototype.

Nano Imprint flow



Vacuum

Roller

UV curing

Demolding

Specifications

Basic configuration	Imprint chamber, Devices for Loading and Unloading of work and replica mold, UV curing and Demolding.
Bubble-free method	Vacuum 10Pa
Pressurizing method	Original Roller with uniform pressure
Demolding method	Original method capable of anisotropic demolding

Experiments and joint development are also supported.
Please contact us.



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